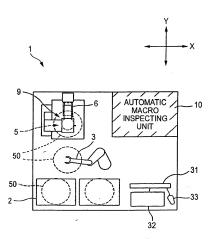
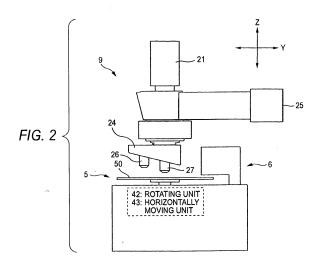


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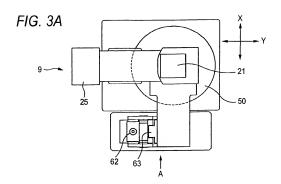
FIG. 1

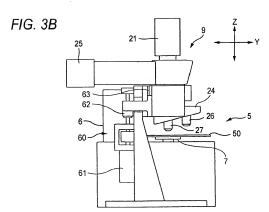


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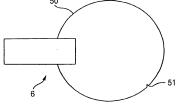
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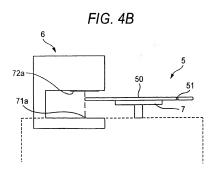




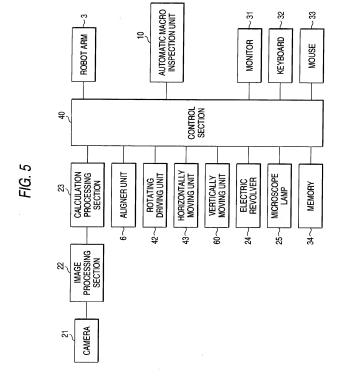
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FIG. 4A

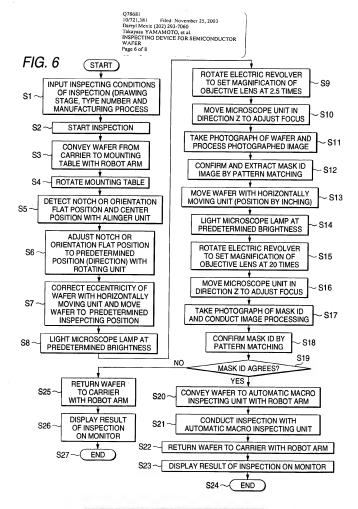




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FIG. 7

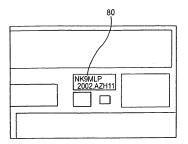
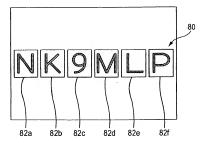


FIG. 8



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FIG. 9A

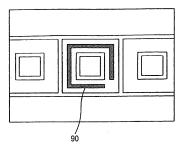


FIG. 9B

